

FORM PTO-1449		ATTY. DOCKET NO. <b>1201.64722</b>	SERIAL NO. <i>662,682</i> 09/00/2000
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		APPLICANT <b>Li et al.</b>	<i>RECEIVED JAN 11 2001 TC 1700 KCI JAN 08 2001 PATENT &amp; TRADEMARK OFFICE</i>
(Use several sheets if necessary)		FILING DATE <b>9/15/2000</b>	

## REFERENCE DESIGNATION      U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
LV	1A 4,092,445	May 30, 1978	Tsuzuki et al.		
LV	1B 5,139,624	Aug. 18, 1992	Searson et al.		
LV	1C 5,206,523	Apr. 27, 1993	Goesele et al.		
LV	1D 5,552,328	Sep. 3, 1996	Orlowski et al.		
LV	1E 5,767,020	June 16, 1998	Sakaguchi et al.		
LV	1F 5,970,361	Oct. 19, 1999	Kumomi et al.		
	1G				
	1H				
	1I				
	1J				
	1K				

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION
						YES
	1L					
	1M					
	1N					
	1O					
	1P					

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

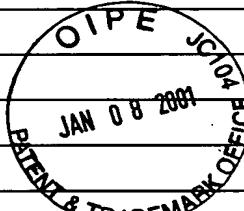
LV	1Q	D. Dimova-Malinovska, M. Sendova-Vassileva, N. Tzenov and M. Kamenova, "Preparation of Thin Porous Silicon Layers by Stain Etching", Thin Solid Films 297, 1997, pp. 9-12.
LV	1R	T. Monguchi, H. Fujioka, K. Ono, Y. Baba, M. Oshima, "Effects of Wet Etching on Photoluminescence of Porous Silicon", Journal of the Electrochemical Society, Vol. 147, No. 2, 2000, pp. 602-605.
LV	1S	J. Salonen, V. Lehto, M. Bjorkqvist, E. Laine, "A Role of Illumination During Etching to Porous Silicon Oxidation", Applied Physics Letters, Vol. 75, No. 6, August 9, 1999, pp. 826-828.

EXAMINER <i>LAN V1N21</i>	DATE CONSIDERED <i>12/3/2001</i>
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FORM PTO-1449		ATTY. DOCKET NO. <b>1201.64722</b>	SERIAL NO. <i>1062682</i> 09 650,611
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		APPLICANT <b>Li et al.</b>	
(Use several sheets if necessary)		FILING DATE <b>9/15/2000</b>	GROUP

## REFERENCE DESIGNATION      U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
2A					
2B					
2C					
2D					
2E					
2F					
2G					
2H					
2I					
2J					
2K					



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## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION
						YES
	2L					
	2M					
	2N					
	2O					
	2P					

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

LV	2Q	T. Tsuboi, T. Sakka, Y.H. Ogata, "Chemical Etching of Porous Silicon in Diluted Hydrofluoric Acid", Solid State Communications, Vol. 109, 1999, pp. 195-199.
	2R	
	2S	

EXAMINER	DATE CONSIDERED
LAN VINH	12/3/2001